AMENDMENT TO THE SPECIFICATION

All amendments are shown with deleted text struckthrough or double bracketed and new text underlined. Please rewrite the paragraph beginning at page 7, line 5 with the following amended paragraph:

It should be further appreciated that MEMS actuator 100 may be incorporated as the underlying electromechanical drive scheme for devices such as those disclosed in U.S. Patent No. 5,319,491 (Figures 16 and 17). By doing so, frustration of the total internal reflection of light may occur within electret layer 103. Referring to Figure 1, it is noted that electret layer 101 in the present invention may correspond to an electret layer embedded just under the surface of the light guide disclosed in U.S. Patent No. 5,319,491 (Figures 16 and 17), in which light is traveling at angles under the critical angle for total internal reflection within the light guide. Figures 16 and 17 are reproduced herein as Figures 2A and 2B. Electret layer 101 is embedded in substrate 301. Electrode 102 may correspond to the conductor 160 disposed on the top of the light guide as disclosed in U.S. Patent No. 5,319,491 (Figures 16 and 17). Electret layer 103 may correspond to an electret layer 302 embedded in the high refractive index deformable dielectric 180 as disclosed in U.S. Patent No. 5,319,491 (Figures 16 and 17). Electrode 104 may be disposed in a fixed spaced-apart relation parallel to electrode 102 with electret layer 103 being disposed between electrodes 102 and 104. In contrast to a global motion of electret layer 103 as an aggregate body, it may undergo deflection and/or deformation under application of the appropriate voltage (see Figures 1A and 1B) to the electrodes 102, 104, propelling the high refractive index 180 in which electret layer 103 (302) may be embedded closer than one wavelength of light to the surface of the light guide 301 in which electret layer 101 is embedded. The light 186 traveling in the light guide 301, which generates an evanescent, inhomogeneous wave along the surface of the light guide, may be able to leap the gap and travel into the portions of the high refractive index dielectric 180, of which electret layer 103 (302) is a part, that are closer than one wavelength from the surface of the light guide 301. The propulsion of electret layer 103 (302) is thus to be understood as embracing not only motion of electret layer 103 as a rigid unit, but also deformations and other mechanical transformations induced by the ponderomotive forces arising under application of appropriate voltages to electrodes 102, 104.